

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :  
Makoto AKIZUKI et al. :  
Serial No. NEW : **Attn: APPLICATION BRANCH**  
Filed August 27, 2003 : Attorney Docket No. 2003-1240

**METHOD FOR FORMING GAS CLUSTER  
AND METHOD FOR FORMING THIN FILM  
(Rule 1.53(b) Continuation  
of Serial No. 10/025,899,  
Filed December 26, 2001)**

**CLAIM OF PRIORITY UNDER 35 USC 119**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:


Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 121983/1995, filed May 19, 1995, Japanese Patent Application No. 244957/1995, filed September 22, 1995, Japanese Patent Application No. 064861/1996, filed March 21, 1996, as acknowledged in the Declaration of this application.

Certified copies of said Japanese Patent Applications are of record in parent application Serial No. 10/025,899, filed December 26, 2001.

Respectfully submitted,

Makoto AKIZUKI et al.

THE COMMISSIONER IS AUTHORIZED  
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